

L Number	Hits	Search Text	DB	Time stamp
-	8	118/719.ccls. and (chamber with pressure with higher with prevent)	USPAT; US-PGPUB	2003/04/06 16:16
-	1	("20010040145").PN.	USPAT; US-PGPUB	2003/02/26 10:13
-	3	((("5709785") or ("6251191") or ("4576830"))).PN.	USPAT; US-PGPUB	2003/04/04 16:58
-	1	("6358377").PN.	USPAT; US-PGPUB	2003/04/04 17:00
-	0	6358377.URPN.	USPAT	2003/04/04 17:00
-	1	("6228439").PN.	USPAT; US-PGPUB	2003/04/04 17:02
-	1	6228439.URPN.	USPAT	2003/04/04 17:03
-	1	6228439.URPN.	USPAT	2003/04/04 17:04
-	329	118/719.ccls. and (conveyor track rail)	USPAT; US-PGPUB	2003/04/04 17:07
-	38	118/719.ccls. and (conveyor track rail) and cluster	USPAT; US-PGPUB	2003/04/04 17:07
-	8	6235634.URPN.	USPAT	2003/04/04 17:19
-	124	414/\$.ccls. and (conveyor track rail) and cluster and (rotat\$3)	USPAT; US-PGPUB	2003/04/04 17:25
-	53	414/\$.ccls. and (conveyor track rail) and cluster and (rotat\$3) and (substrate wafer semiconductor)	USPAT; US-PGPUB	2003/04/04 18:36
-	72	4643629.URPN.	USPAT	2003/04/04 17:53
-	72	4643629.URPN.	USPAT	2003/04/04 17:59
-	28	4674621.URPN.	USPAT	2003/04/04 18:00
-	481	414/\$.ccls. and ((conveyor track rail) same (turntable))	USPAT; US-PGPUB	2003/04/04 18:36
-	12	414/\$.ccls. and ((conveyor track rail) same (turntable with rotat\$3) same (substrate wafer semiconductor))	USPAT; US-PGPUB	2003/04/04 18:55
-	677	(414/749.1-749.6).CCLS.	USPAT; US-PGPUB	2003/04/06 14:52
-	55	(414/749.4).CCLS.	USPAT; US-PGPUB	2003/04/06 15:09
-	279	(414/936).CCLS.	USPAT; US-PGPUB	2003/04/06 15:55
-	72	4643629.URPN.	USPAT	2003/04/06 15:17
-	3548126	414/939.ccls. no ((414/936).CCLS.)	USPAT; US-PGPUB	2003/04/06 15:56
-	485	414/939.ccls.	USPAT; US-PGPUB	2003/04/06 15:56
-	426	414/939.ccls. not ((414/936).CCLS.)	USPAT; US-PGPUB	2003/04/06 15:57
-	426	414/939.ccls. not ((414/936).CCLS.)	USPAT; US-PGPUB	2003/04/06 15:57
-	69	3874525.URPN.	USPAT	2003/04/06 16:07
-	414	118/719.ccls. and ((wafer semiconductor substrate) with vertical\$3)	USPAT; US-PGPUB	2003/04/06 17:41
-	28	4717461.URPN.	USPAT	2003/04/06 16:28
-	62	4500407.URPN.	USPAT	2003/04/06 20:22
-	1	("5888303").PN.	USPAT; US-PGPUB	2003/04/06 17:43
-	2	118/719.ccls. and (rotat\$3 with axis with vertical\$3 with (transfer\$3 transport\$3) with chamber)	USPAT; US-PGPUB	2003/04/06 17:55
-	91	118/719.ccls. and (vertical\$3 with (transfer\$3 transport\$3) with chamber)	USPAT; US-PGPUB	2003/04/06 17:57
-	802	118/730.ccls.	USPAT; US-PGPUB	2003/04/06 17:58
-	55	156/345.55.ccls.	USPAT; US-PGPUB	2003/04/06 18:00
-	125	156/345.55.ccls. 156/345.54.ccls.	US-PGPUB USPAT; US-PGPUB	2003/04/06 18:00
-	155	414/\$.ccls. and (conveyor track rail) and cluster	USPAT; US-PGPUB	2003/04/06 18:07
-	43232	118/\$.ccls. 156/3453\$.ccls. 414/\$.ccls. and ((vertical\$3 with (substrate wafer semiconductor) with (transfer\$3 transport\$3)) same cluster)	USPAT; US-PGPUB	2003/04/06 19:09

-	16	(118/\$.ccls. 156/3453\$.ccls. 414/\$.ccls.) and ((vertical\$3 with (substrate wafer semiconductor) with (transfer\$3 transport\$3)) same cluster)	USPAT; US-PGPUB	2003/04/06 19:10
-	5	5738767.URPN.	USPAT	2003/04/06 19:12